

ABSTRACT

5 A sensor on a semiconductor wafer is used as a
process monitor and a capacitor is employed as a power
supply for the sensor. The capacitor can be formed by
stacking a poly-silicon layer and a silicon nitride layer
on the wafer. A timer can be used to specify an
operation time or an operation timing, etc. Furthermore,
unauthorized use is prevented by storing a keyword in an
10 ROM of the process monitor.